

東京大学が進める光赤外線分野の 基礎開発研究

Basic developments on optical-infrared astronomy
driven by the University of Tokyo

東京大学 天文学教育研究センター
Institute of Astronomy, the University of Tokyo

酒向 重行 (SAKO, Shigeyuki)



Framework of developments in U-Tokyo

Observatory in Atacama, Chile
Overseas base

TAO
miniTAO

Staff: 0
TS: 0
PD: 0
ST: 0

6.5-m telescope (future plan)
1.0-m telescope

Observatory in Kiso, Japan
Domestic base

KISO

Staff: 0
TS: 3
PD: 2
ST: 0

1.0-m telescope

Headquarter in Tokyo

Mitaka(loA)

Staff: 14†
TS: 1
PD: 3†
ST: 25(16)

Hongo

Staff: 9†
TS: 0
PD: 1†
ST: 15(9)

Developments of instruments and
basic technologies are mainly
proceeding at Mitaka and Kiso.

† Including persons on other research fields

Instruments developed by U-Tokyo

- **Development phase**

for TAO 6.5-m and Subaru 8.2-m	SWIMS	<i>NIR camera and spec. with MOS</i>
	MIMIZUKU	<i>MIR camera and spec.</i>
for Kiso Schmitt 1.0-m	KWFC	<i>Wide field CCD imager</i>
for KyotoSangyo-U 1.3-m	WINERED	<i>NIR high resolution spec.</i>

- **Observation phase**

on miniTAO 1.0-m	ANIR	<i>NIR camera</i>
	MAX38	<i>MIR camera</i>
on Kiso Schmitt 1.0-m	2kCCD	<i>Wide field CCD imager</i>
on Hokkaido-U 1.6-m	NICE	<i>NIR mid resolution spec.</i>
on Hiroshima-U 1.5-m	DMC	<i>15-bands CCD camera</i>

List of instruments whose PI is in U-Tokyo

New technologies

from the instrument projects

- **SWIMS** → **Micro shutter**
- **MIMIZUKU** → **Metal mesh filter**
MAX38 → **Moth-eye optics**
→ **Cold Tip-Tilt**
- **KWFC** → **CCD controller**
→ **Filter changer with Robotic arm**
- **WINERED** → **Immersion grating**

Electrostatic drive type Micro shutter array

□ Micro shutter array

- Array of small shutters (0.1 to 1 mm size)
- Can open a shutter at an arbitrary position
- Use as a MOS slit → Simplify a MOS system

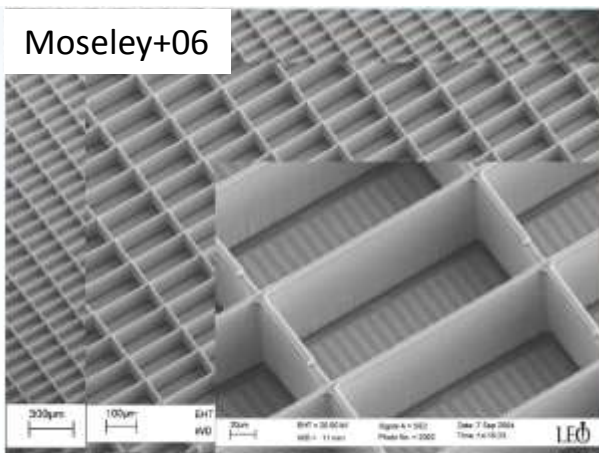
Motohara et al.

□ Array for JWST (Goddard) is closest to practical use

- scanning with magnets
- complex system

□ In this study, **Electrostatic drive type** has been developed.

Moseley+06



King+05

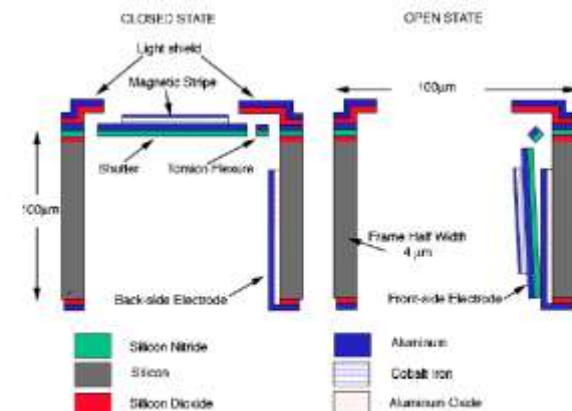
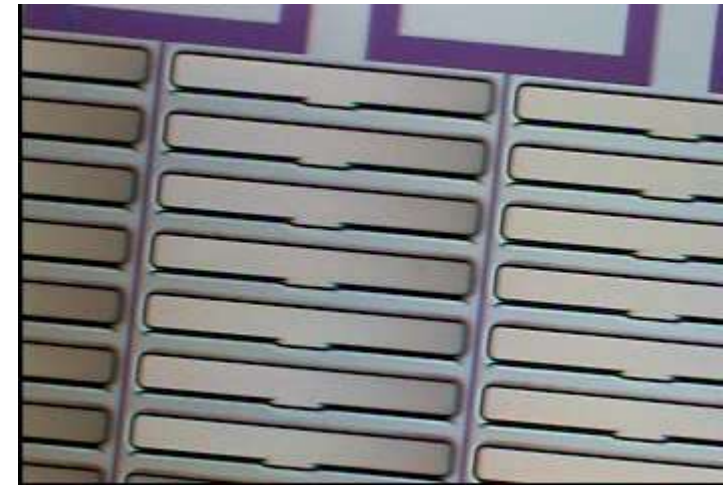


Figure 1. Schematic cross-section of a shutter cell in the closed and open states. Front-side (top) will face light objects in space whose spectra will be determined via NIRSpec placed on the back-side (bottom) of the array.

Electrostatic drive type Micro shutter array

□ IoA, U-Tokyo + Institute of Industrial Science, U-Tokyo + NAOJ

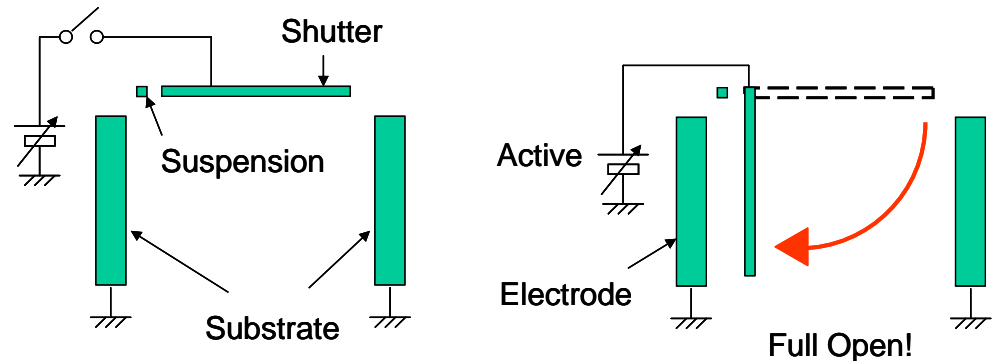
- Since 2004
- With **electrostatic force** (>100V is necessary), not magnetic force
- Simple addressing method
- Succeeded in opening and closing shutters.



1mm x 0.1mm

□ Next steps

- ✓ Structure to prevent light leak
- ✓ Stable behavior
- ✓ Larger format



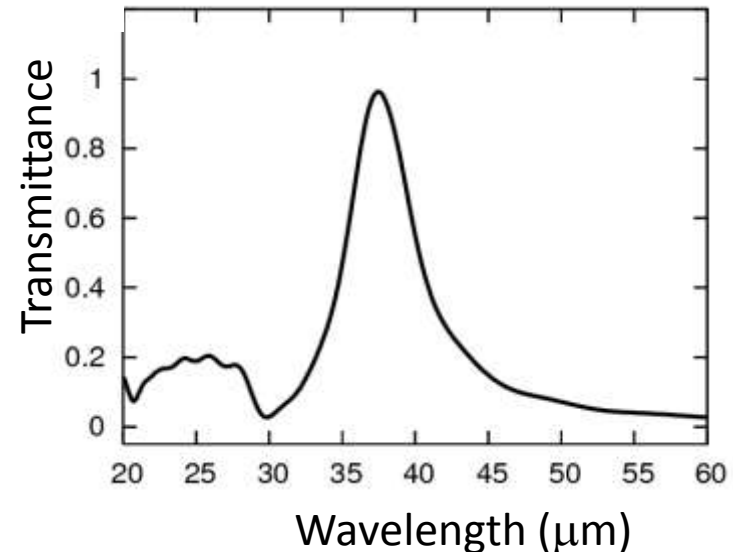
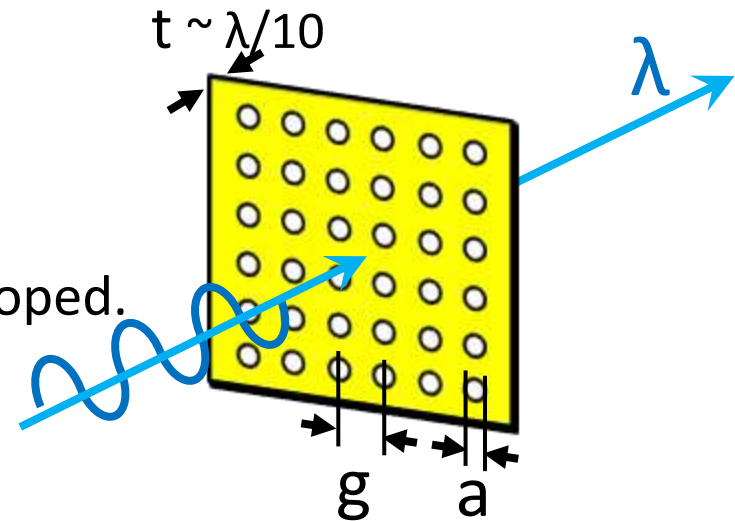
Metal mesh filter

- No good optical filters in 25 - 40 μm
 - No transparent material in 25 – 40 μm
 - ✗ Multi-layer interference method
 - In this study, MIR filters **without transparent material** have been developed.

- Metal mesh filter

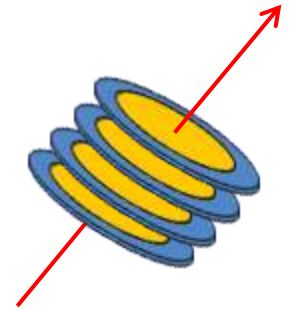
- Thin metal film with hole array
- **Band-pass profile ($R \sim 10$)**
- **Peak transmittance** of $\sim 100\%$
- Surface Plasmon-Polariton (SPP) effect

Miyata & Sako et al.

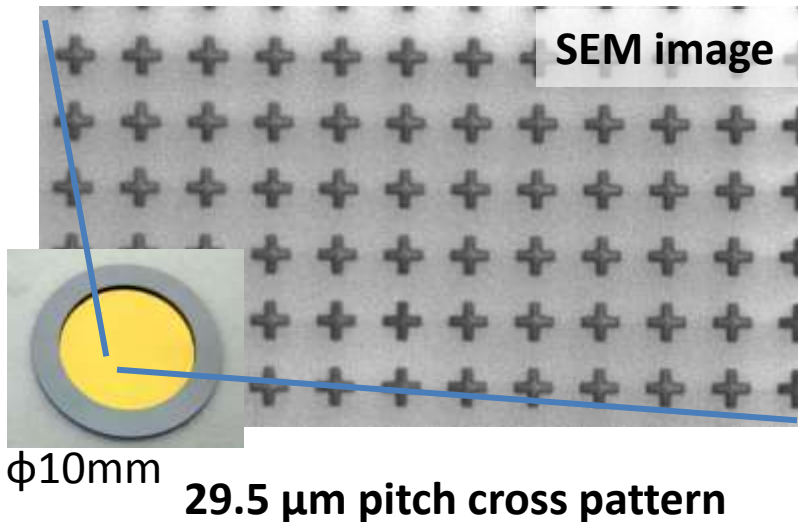
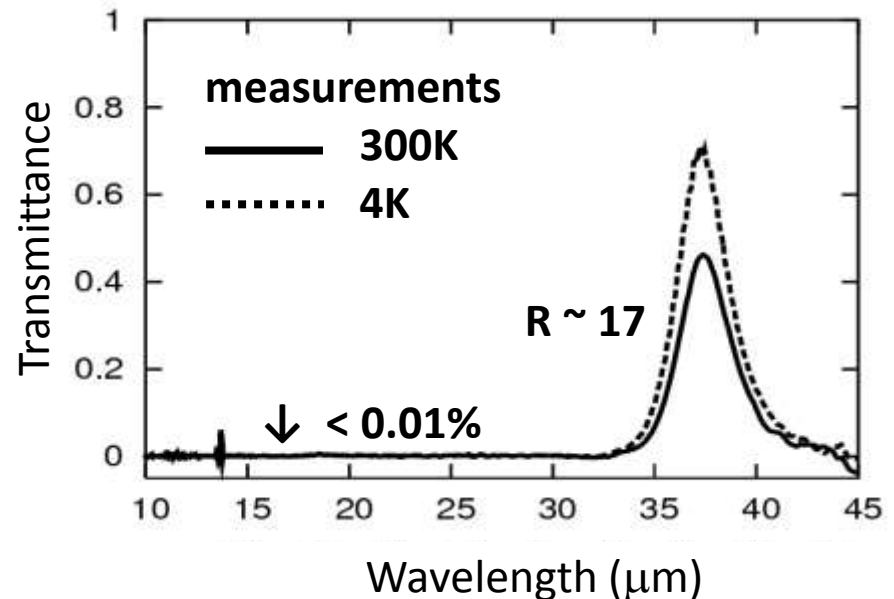


Metal mesh filter

- ❑ **IoA, U-Tokyo + NTT-Advanced Technology + JAXA & NAOJ**
- ❑ Since 2006.
- ❑ FDTD simulation & Photolithography fabrication
- ❑ Succeeded in obtaining a peak trans. of $> 90\%$ and $R \sim 10$
- ❑ Blocking ratio of $< 0.01\%$ by stacking 4 filters
- ❑ used in miniTAO/MAX38.
- ❑ Next steps \rightarrow Increase in Strength, Larger aperture



stacking 4 filters



Silicon Moth-eye

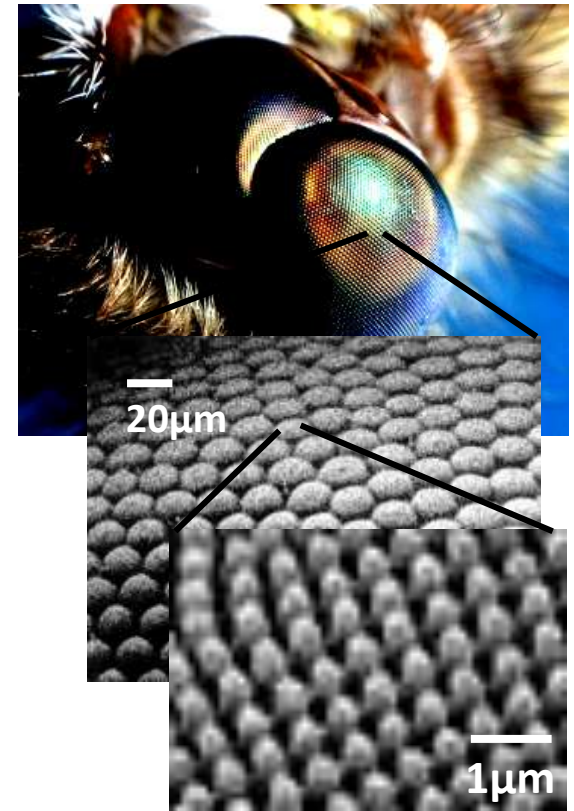
Sako & Miyata et al.

- ❑ No good optical substrate in 25 - 40 μm
- ❑ **Silicon** is one of the few potential candidates

Problem

- High refractive index ($n \sim 3.4$)
→ **High reflection loss** (30% on one surface)
- **AR-coating is not available**
(the same reason of filters)
- ❑ In this study, AR surfaces **without multilayer interference** have been developed.
- ❑ Moth eye anti-reflection structure
 - Sub-wavelength scale structure
 - Broadband Anti-reflection effect
 - Single material

Compound eye of Moth

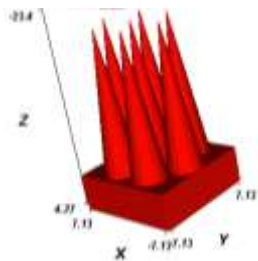


Pillar structures with a pitch of 0.5 – 1 μm on the surface of one eye

Silicon Moth-eye

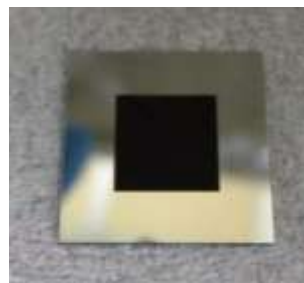
- ❑ **IoA, U-Tokyo + NTT-Advanced Technology + JAXA & KAKENHI**
- ❑ Since 2009
- ❑ RCWA simulation & Photolithography and RIE fabrication
- ❑ Succeeded in obtaining a trans. of **98% in 25 - 40 μm** on one surface.
- ❑ Next step
 - ✓ Both side, Moth-eye on Lens, Grism, and window, and for NIR.

Design for MIR

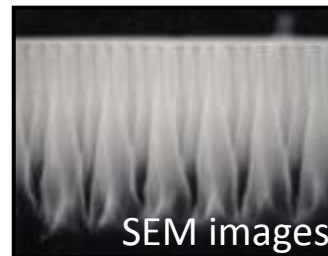
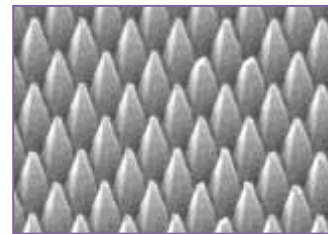


- circular cone
- 60° adjacent
- pitch 5 μm
- length 20 μm

Fabricated Silicon Moth-eye

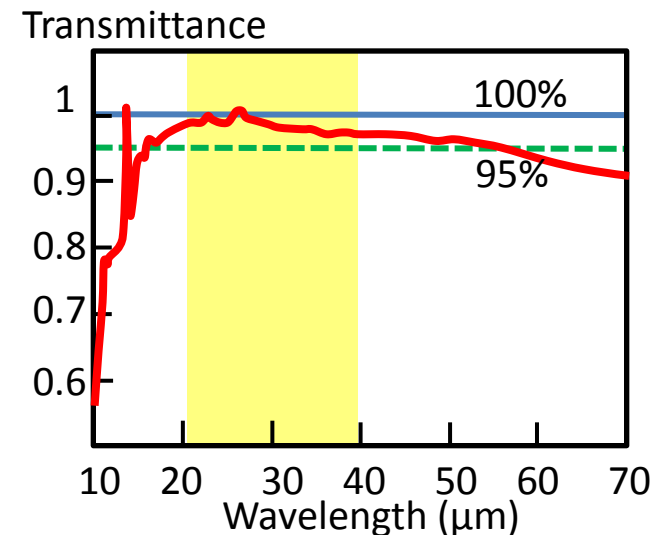


Overview
10 x 10mm
Visible image



SEM images

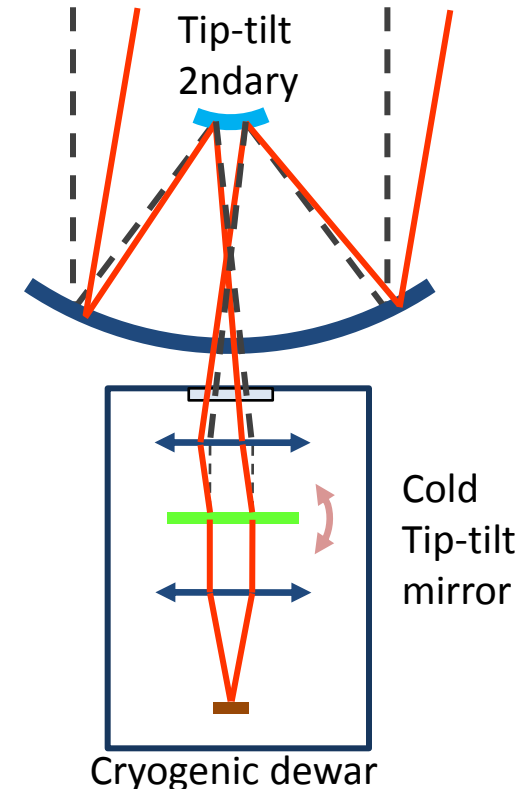
Results (measurement)



Cold Tip-Tilt Mirror

- ❑ Cryogenic opt-mechatronics is a key technology in TMT and SPICA era
 - Expand the capability of infrared instruments
- ❑ High stability and low power are needed
- ❑ In this study, **cryogenic tip-tilt** (chopper) mirror for MIR observations has been developed.
- ❑ Cold tip-tilt (chopper) system
 - No need tip-tilt motion of 2ndary mirror
 - Enables tip-tilt observations in space (to remove fast vibration generated by refrigerators)

Nakamura et al.



MIR observation with chopping techniques
Typical chopping Freq. is 1 – 10Hz

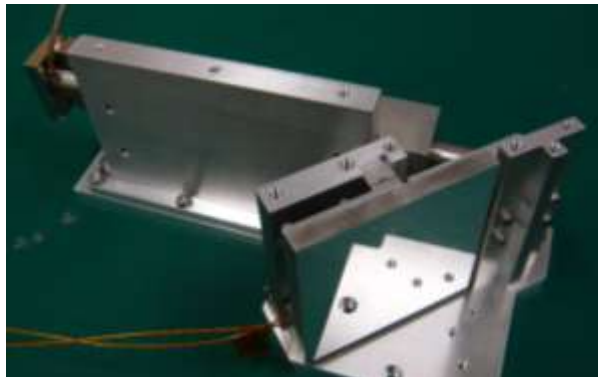
Cold Tip-Tilt Mirror

- ❑ **IoA, U-Tokyo + Fuji ceramics + JAXA & KAKENHI**
- ❑ Since 2005.
- ❑ **Cryogenic piezo actuators** were developed .
Stroke is extended by a factor of **2.7** at 7K
- ❑ Succeeded in driving the chopper with
max **5 Hz** and **15"** amplitude, and $< 100\text{mW}$ at $< 20\text{K}$.
- ❑ Used in miniTAO/MAX38
- ❑ Next step \rightarrow 2-axis type, larger amplitude, faster feedback

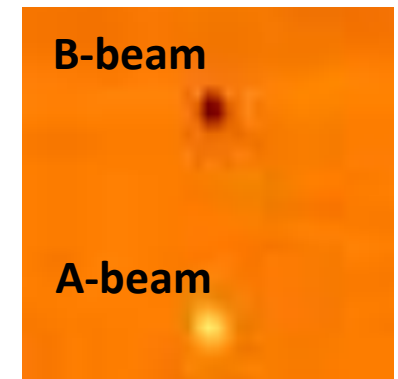
Driving test of new piezos



Overview of Cold Tip-Tilt system



Observation image



New CCD controller

Sako et al.

- ❑ No suitable controller for 1 – 8 CCDs system
- ❑ **Almost projects driven by University need small-mid sized system**, not larger like HSC.
- ❑ In this study, new CCD controller for small-med sized system (**KAC**: Kiso array controller) has been developed.

- ❑ Kiso wide field camera (KWFC)
 - Next generation **open-use** instrument on Kiso 1m telescope
 - Wide F.O.V. (**2deg x 2deg**)
 - 8CCDs of 2k x 4k pixels
 - 4 SITE and 4MIT CCDs from NAOJ
 - Opened in Apr. 2012



New CCD controller

- **IoA, U-Tokyo + Several Universities and Institute in Japan**
(Hokkaido-U, Kyoto-U, AoyamaGakuin-U, and JAXA) + **NAOJ**
- Since 2009
- Succeeded in taking astronomical images with Kiso/KWFC
- **Welcome participation of this project**

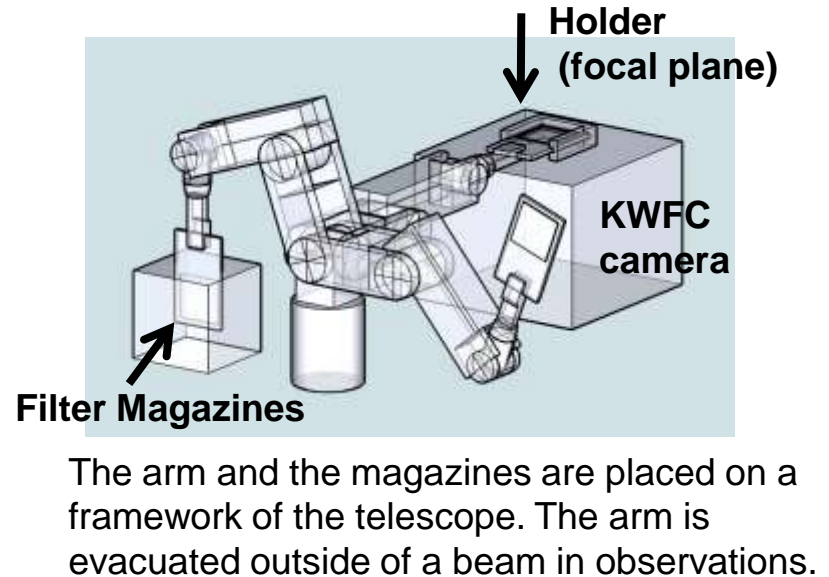
- Development plan
 - Redesign the analog circuit for **Hamamatsu CCDs** (2011/1-8)
 - Installed into
 - Spectrometer developed by Hokkaido-U and Kobe-U
 - Kyoto 3D instrument for Subaru
 - Test systems for Infrared and X-ray satellites



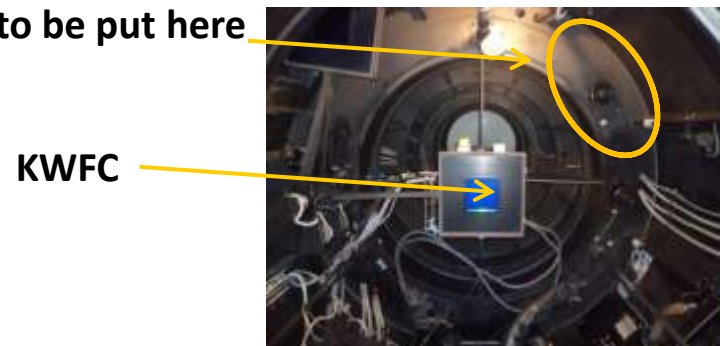
KAC analog boards for 8 CCDs

Filter exchanger with Robotic arm

- ❑ **IoA, U-Tokyo + Mitsubishi electronics system & service + Sumitomo foundation**
- ❑ Since 2010
- ❑ Filter exchanger is set at the **prime focus** of KISO Schmitt telescope
- ❑ Uses an **industrial robotic arm**
- ❑ Stores 16 filters (158 x 158 x 15mm) in the magazine box
- ❑ Realizes a compact and lightweight system
- ❑ **Put an unique ideas to practical use**



Filter exchanger to be put here



Inside the Schmidt telescope from the primary side

Immersion grating for NIR

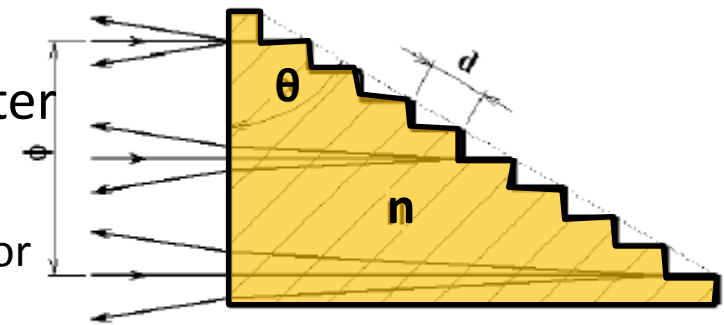
- Immersion grating
 - ✓ A sort of reflection type grating
 - ✓ Diffraction side is filled with 'n'

Ikeda and Kobayashi et al.

- Resolution and Physical size of spectrometer

$$\phi \propto R \cdot D / n$$

ϕ : beam size
 D : diameter of prime mirror
 R : spectral resolution



- High resolution spectroscopy with Large telescope

- **a size of optics \propto resolution**

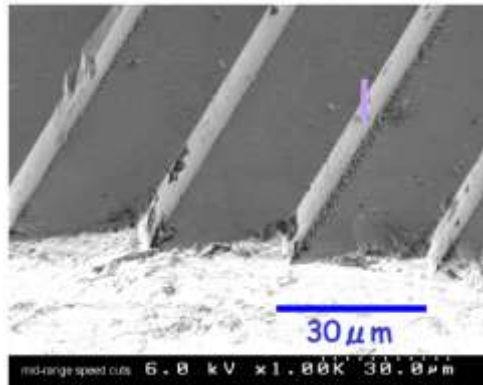
→ large and heavy instrument → high cost

- Immersion grating with large 'n' can downsize the optics

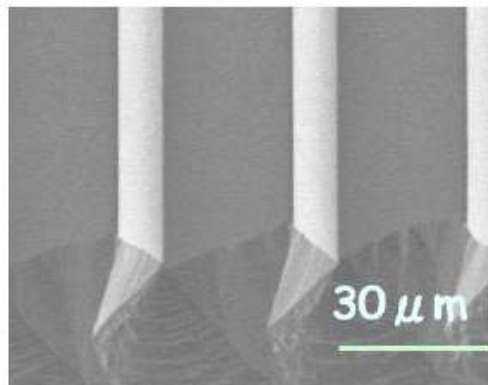
→ In this study, immersion gratings for NIR have been developed.

Immersion grating for NIR

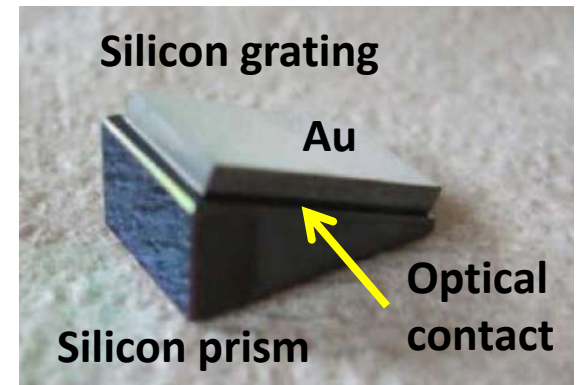
- IoA, U-Tokyo + Photocoding + KyotoSangyo-U + NTT-Advanced Technology + Lawrence Livermore National Laboratory + JAXA & NAOJ
- Since 2005
- Two types of substrate : **ZnSe** (broad band), **Silicon** (high n)
- Fabrication processes of grooves
 - ZnSe → nano precision **fly-cutting** technique (LLNL)
 - Silicon → **anisotropic etching** + photolithography (NTT-AT)
- Succeeded in making high quality grooves with both methods
- Next steps: improve diffraction efficiency and assemble the elements



Grooves on ZnSe

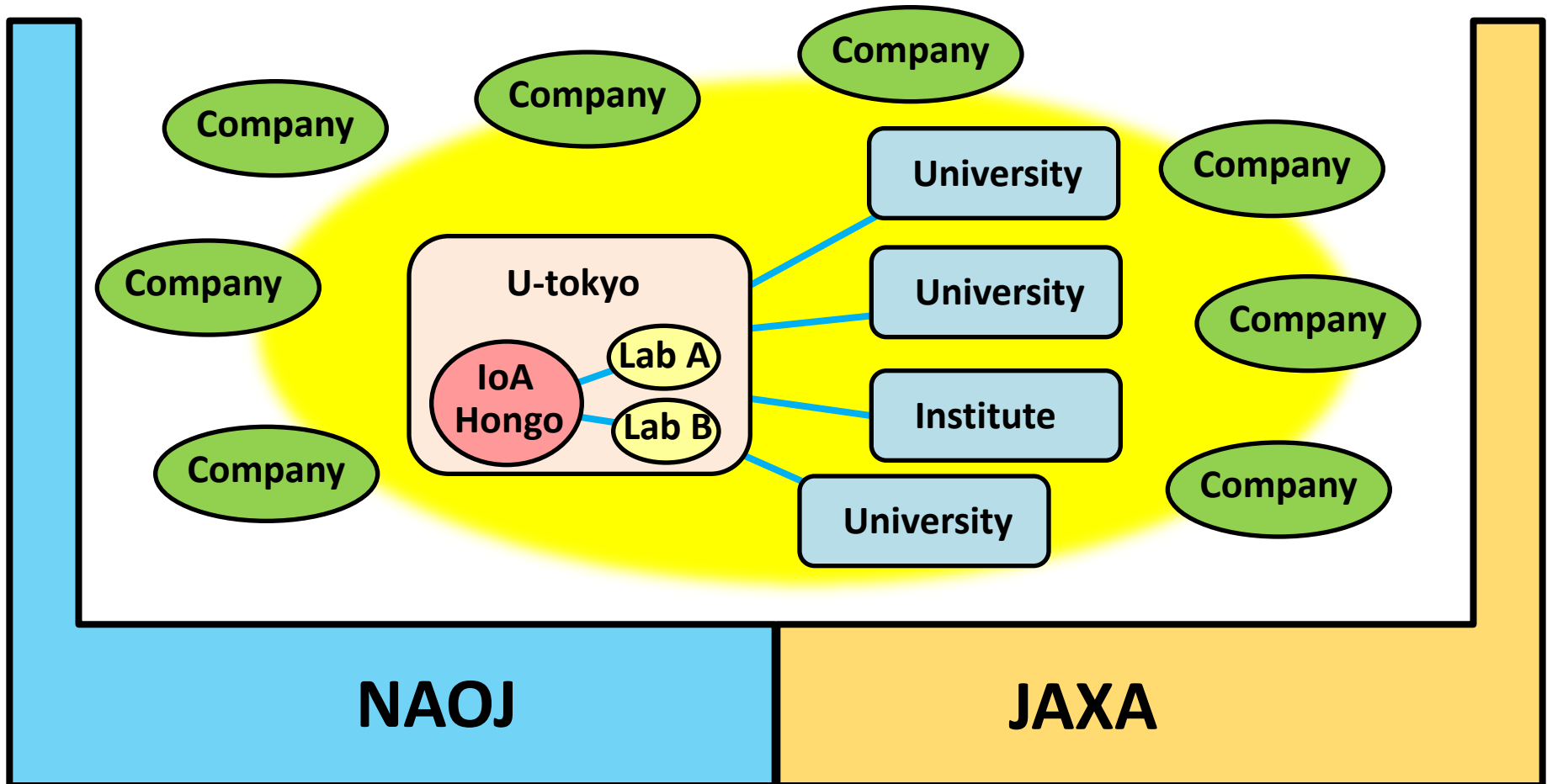


Grooves on Silicon



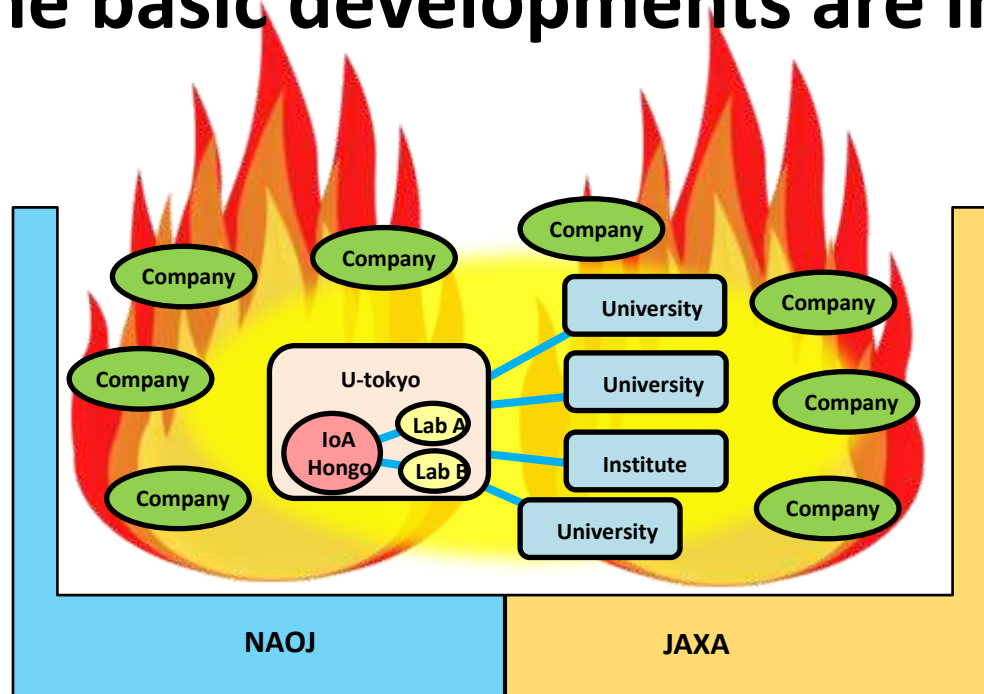
Silicon immersion grating

Basic developments expand community and build a strong foundation



Universities are highly-responsive

- ✓ While energy sources are present, the responses are continued.
- ✓ Continuous and widespread supports to the basic developments are important.



Summary

- ❑ U-Tokyo has developed several new basic technologies in promoting mid-small sized instrument projects.
- ❑ The basic developments have expanded the community on Japanese astronomy.
- ❑ Continuous and widespread supports to the basic development are important to build a strong foundation toward TMT era.
- ❑ While energy sources are present, responses between Universities are continued.

